

S1: (arrow marks) $R_a = 50\% \pm 3\%$ @ 650-1050 nm + $R_p = 35\% \pm 3\%$ @ 650-1050 nm + $R_s = 67\% \pm 3\%$ @ 650-1050 nm, AOI 45 deg.
S2: ARs <2% @ 650-1100 nm + ARp < 1.5% @ 650-1100

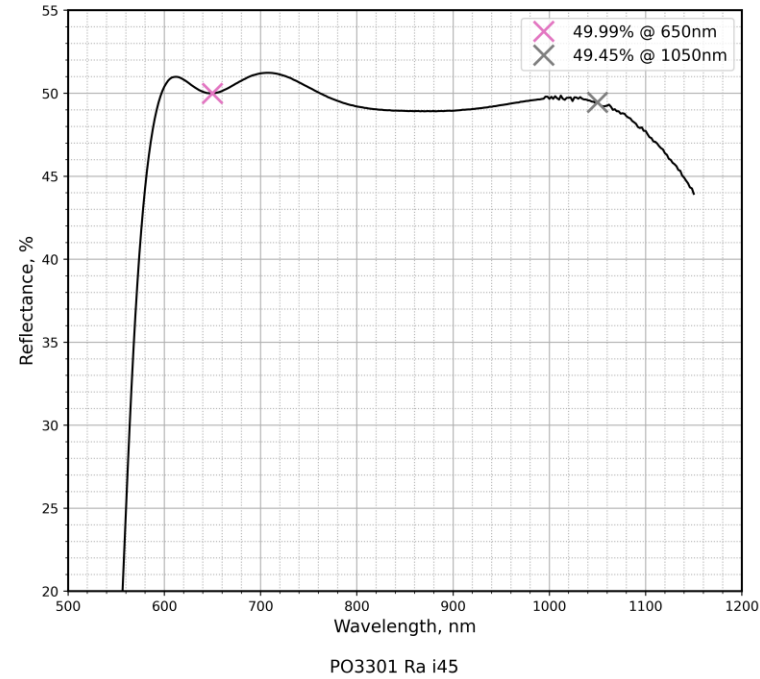
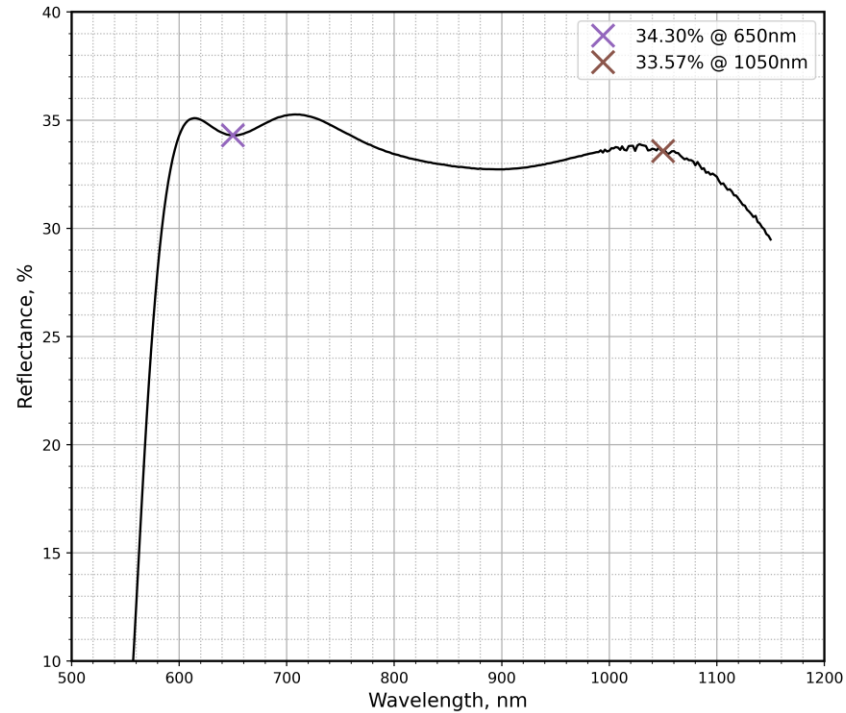


Fig. 1.

SIDE MEASURED: S1 only (grinded witness sample)

COMMENTS: Margin of measurement error: +/-0.25%

S1: (arrow marks) $R_a = 50\% \pm 3\%$ @ 650-1050 nm + $R_p = 35\% \pm 3\%$ @ 650-1050 nm + $R_s = 67\% \pm 3\%$ @ 650-1050 nm, AOI 45 deg.
S2: ARs <2% @ 650-1100 nm + ARp < 1.5% @ 650-1100



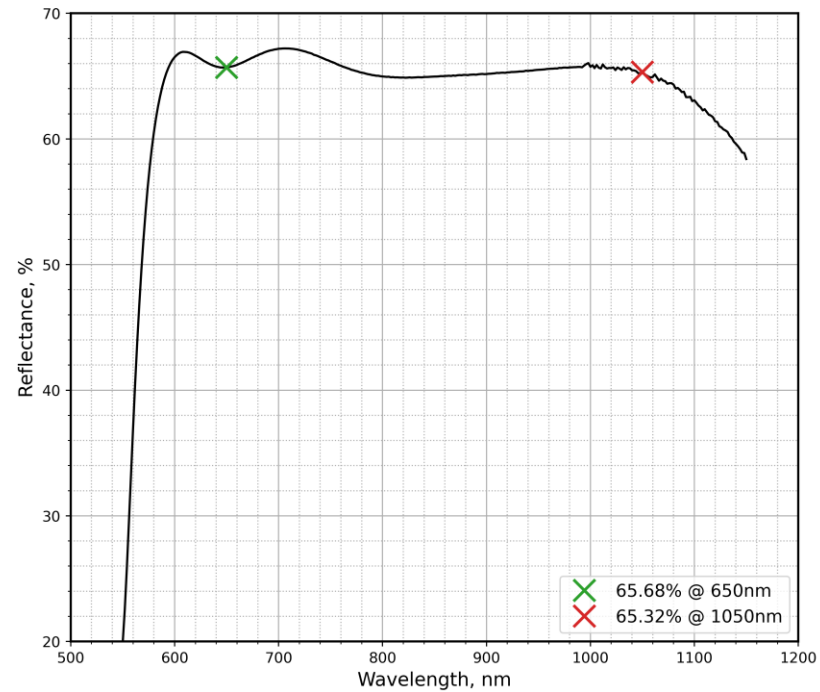
PO3301 Rp i45

Fig. 2.

SIDE MEASURED: S1 only (grinded witness sample)

COMMENTS: Margin of measurement error: $\pm 0.25\%$

S1: (arrow marks) $R_a = 50\% \pm 3\%$ @ 650-1050 nm + $R_p = 35\% \pm 3\%$ @ 650-1050 nm + $R_s = 67\% \pm 3\%$ @ 650-1050 nm, AOI 45 deg.
 S2: ARs <2% @ 650-1100 nm + ARp < 1.5% @ 650-1100



PO3301 Rs i45

Fig. 3.

SIDE MEASURED: S1 only (grinded witness sample)

COMMENTS: Margin of measurement error: +/-0.25%

S1: (arrow marks) $R_a = 50\% \pm 3\%$ @ 650-1050 nm + $R_p = 35\% \pm 3\%$ @ 650-1050 nm + $R_s = 67\% \pm 3\%$ @ 650-1050 nm, AOI 45 deg.
S2: ARs $< 2\%$ @ 650-1100 nm + ARp $< 1.5\%$ @ 650-1100

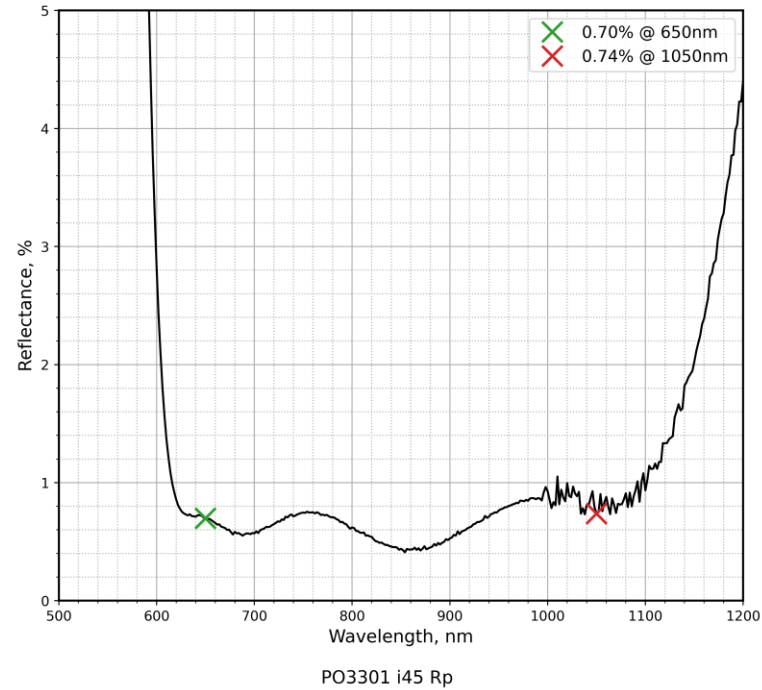
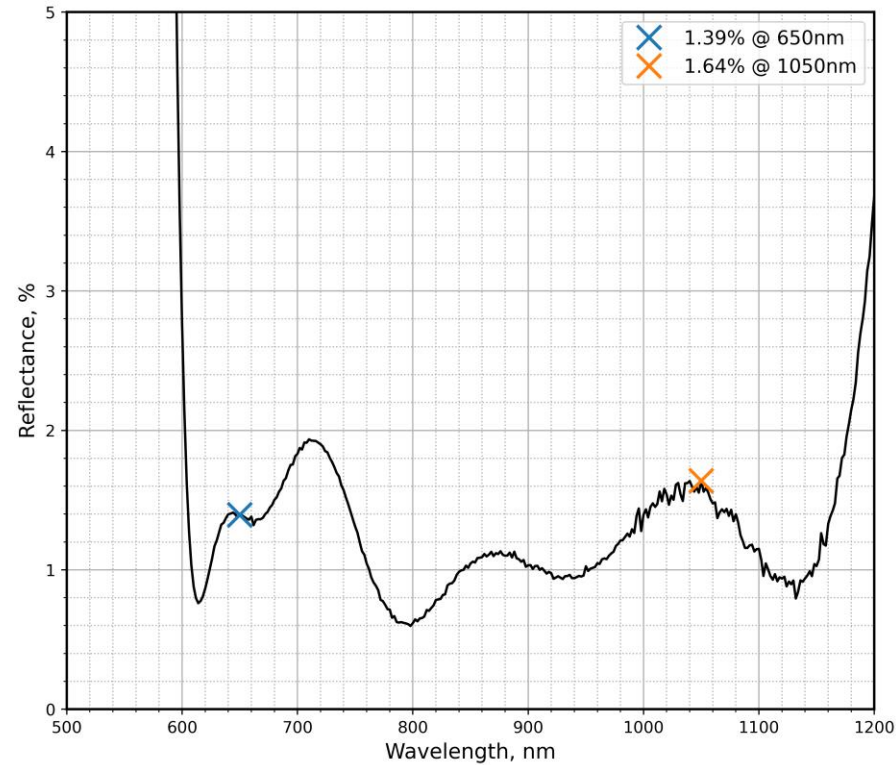


Fig. 4.

SIDE MEASURED: S2 only (grinded witness sample)

COMMENTS: Margin of measurement error: $\pm 0.25\%$

S1: (arrow marks) $R_a = 50\% \pm 3\%$ @ 650-1050 nm + $R_p = 35\% \pm 3\%$ @ 650-1050 nm + $R_s = 67\% \pm 3\%$ @ 650-1050 nm, AOI 45 deg.
 S2: ARs $< 2\%$ @ 650-1100 nm + ARp $< 1.5\%$ @ 650-1100



PO3301 i45 Rs

Fig. 5.

SIDE MEASURED: S2 only (grinded witness sample)

COMMENTS: Margin of measurement error: $\pm 0.25\%$